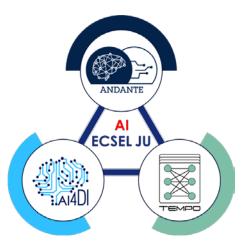
International Workshop on Embedded Artificial Intelligence Devices, Systems, and Industrial Applications (EAI)



ECSEL JL

Milan, Italy 19 September 2022

International Workshop on Embedded Artificial Intelligence Devices, Systems, and Industrial Applications (EAI)



Artificial Intelligence: the impact in the semiconductor world

Sara Loi - STMicroelectronics







- AI opportunities and challenges
- Applications enabled
- Al for decision making in factory/building
- Al in semiconductor manufacturing

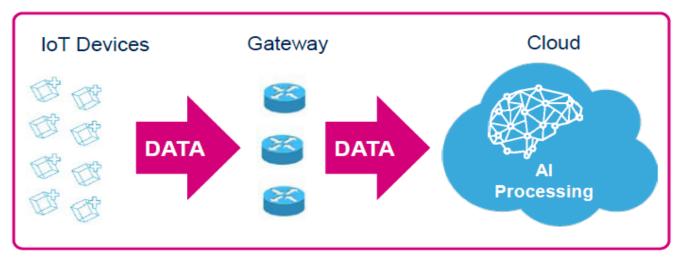


• Al opportunities and challenges

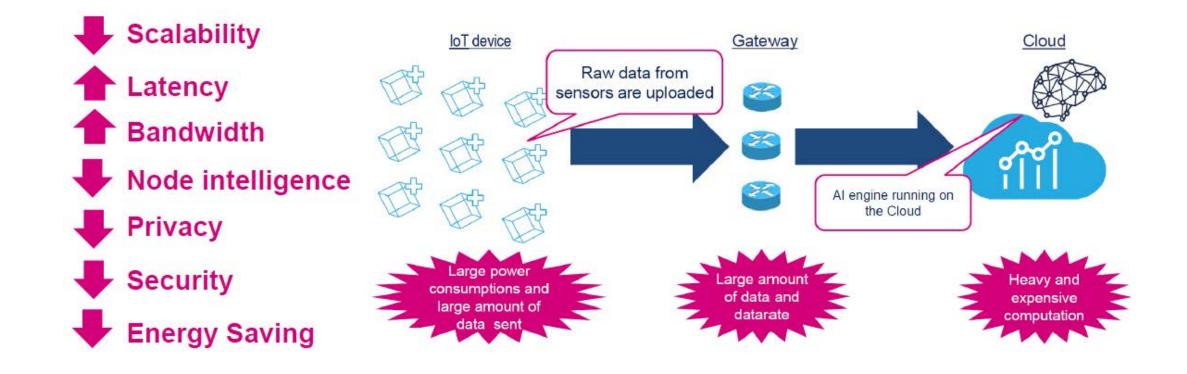
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Al opportunities

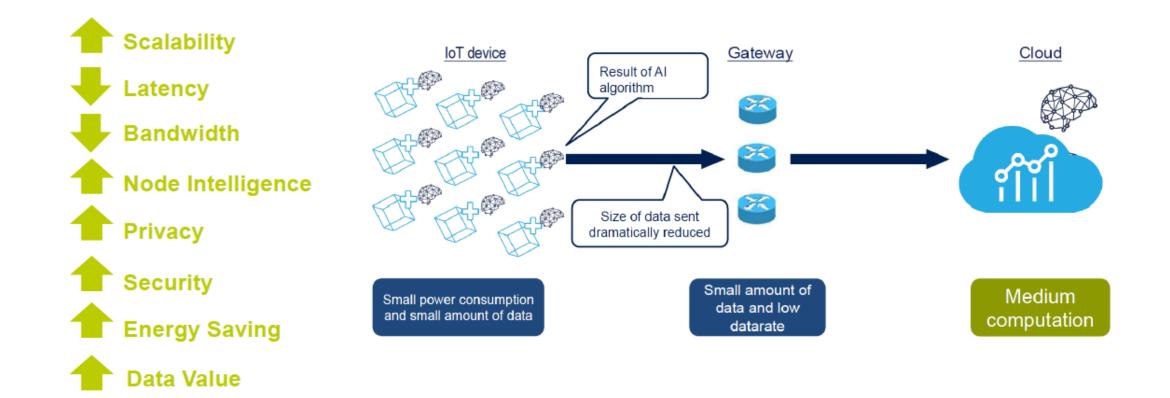




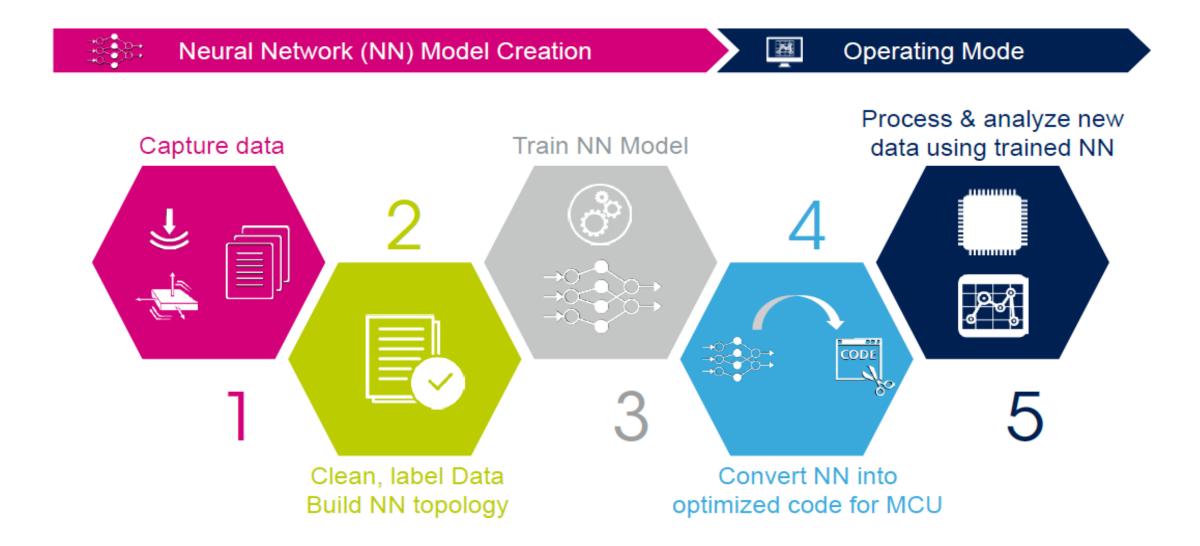
...and challenges: centralized approach



Distributed approach: Al@ the Edge/Node



Key steps behind neural networks





- Al opportunities and challenges
- Applications enabled
- Al for decision making in factory/building
- Al in semiconductor manufacturing

Applications enabled

SOUND BASED

Sound event classification

- Home alarms
- Machine anomaly

Context awareness

Intrusion
detectionIntrusion
detectionIntrusion
detectionIntrusion
detection

COMPUTER VISION ON MCUs

th

HMI

- Gesture recognition
- Face Recognition
- Emotion Recognition 5





Predictive maintenance

- Smoke detection
- Product defect detection



Image processing

- Characters and digits recognition
- Recognize field pests, disease



- Vehicular environment
- Factory activity
- Human presence detection

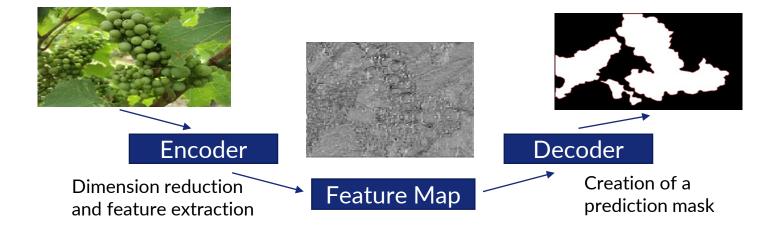


Autonomous environment-aware Robot



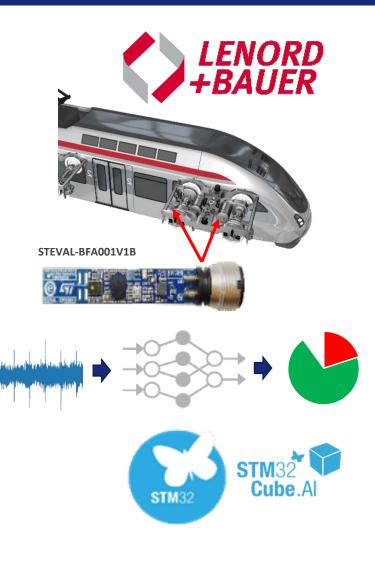


- Integration of cameras to the robot for
 - ✓ Grape/flower detection and counting
 - ✓ Disease detection on leaves/grapes
- AI based monitoring systems to provide guidance and advice



Predictive Maintenance relying on embedded AI

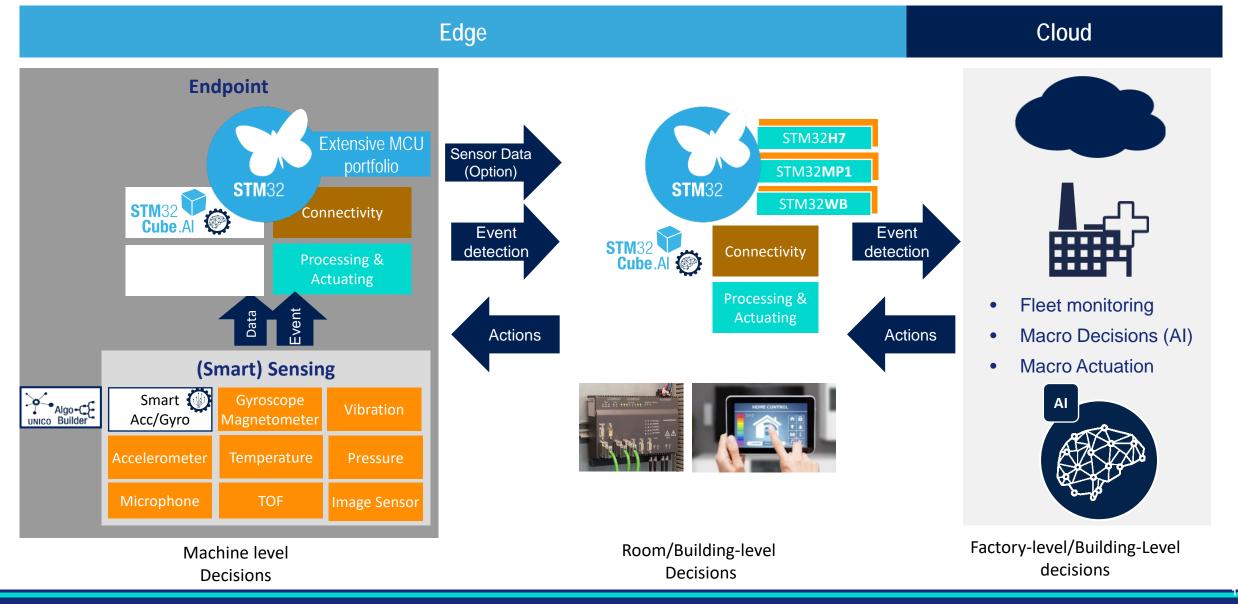
- Joint project STMicroelectronics Lenord Bauer
- Accelerometer data to monitor wheels (bearing) vibrations anomalies.
- A NN, running on the MCU of the node, provides alarm in critical conditions





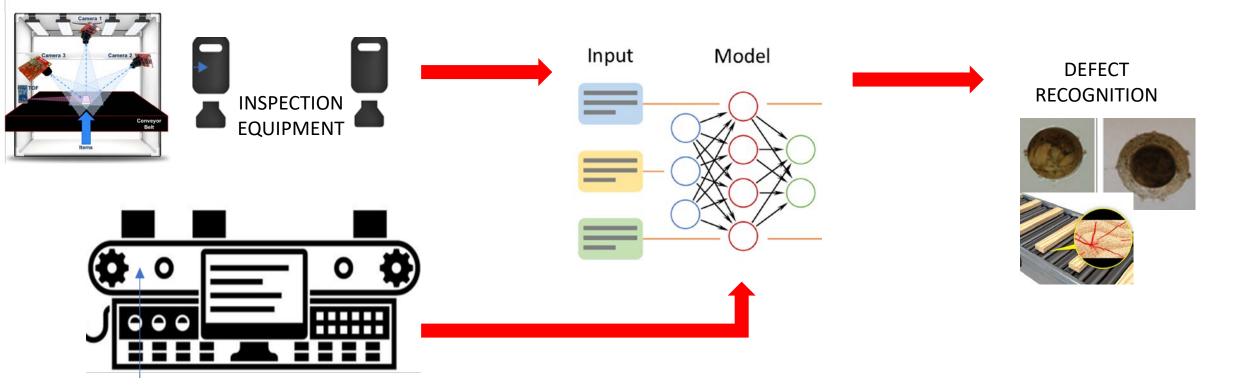
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Distributed AI for factory/building decisions



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Al-based quality control for woodwork production process



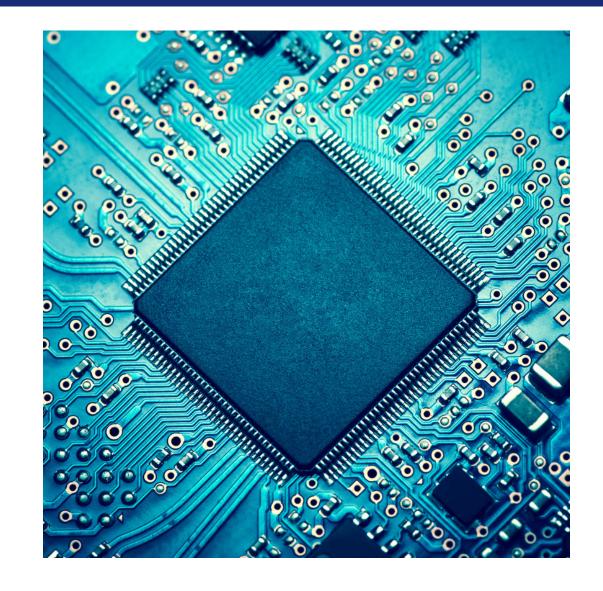
- An AI based monitoring systems for quality control in production
- Distributed learning mechanism for continuous training



- Al opportunities and challenges
- Applications enabled
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Data analytics and AI for manufacturing excellence

- Industrialize manufacturing Data & Analytics capabilities
- Improve manufacturing **Quality** and **Yield**
- Improve equipment (& People) productivity and reduce manufacturing cost



Overall structure

Use Cases

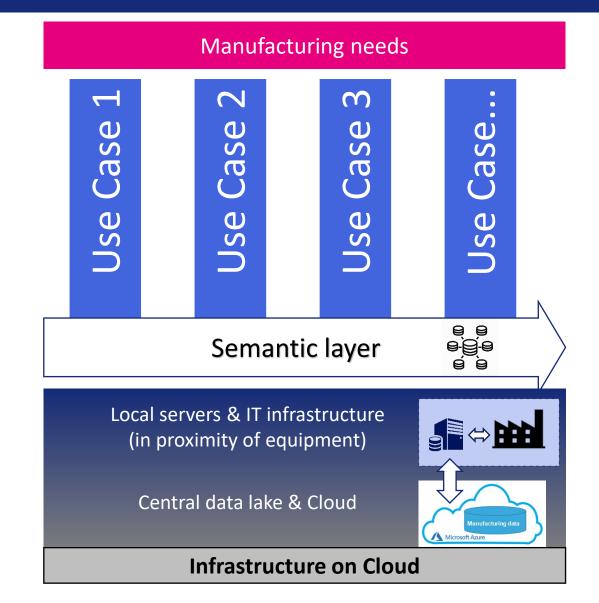
- Develop and deploy use cases
- Review with site experts

Semantic layer

• Provide access to data all over the manufacturing chain

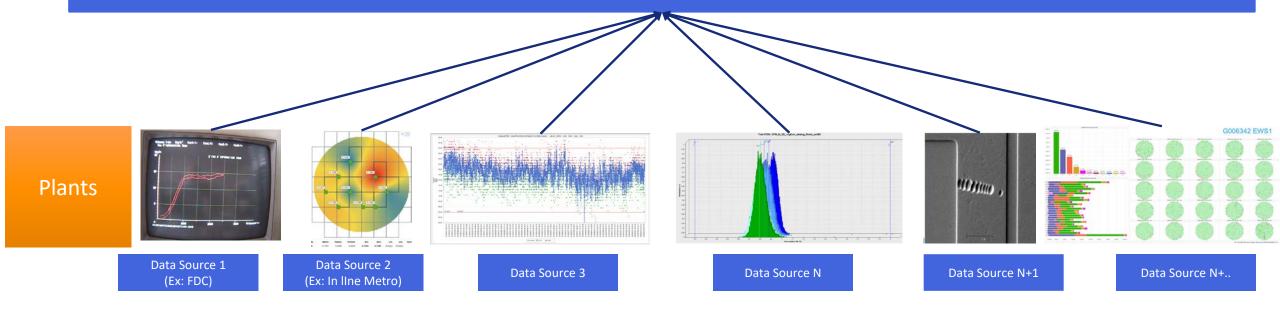
IT infrastructure

- Cloud environment to host Manufacturing Data and local servers in each plant
- Central to exercise (train) and adjust (tune) models and tools

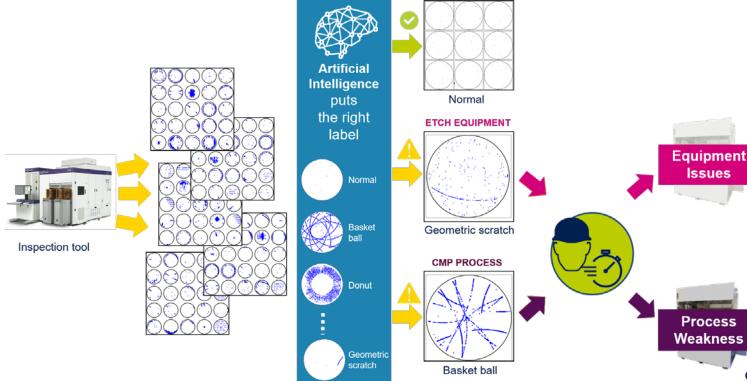


Semantic

- Contextualize the data to activate interactions between various domains across the whole chain
- Common language, managed interactions
- **Cross sites/transportability** of Use Cases



Use case: Automatic Wafer Classification (AWC)

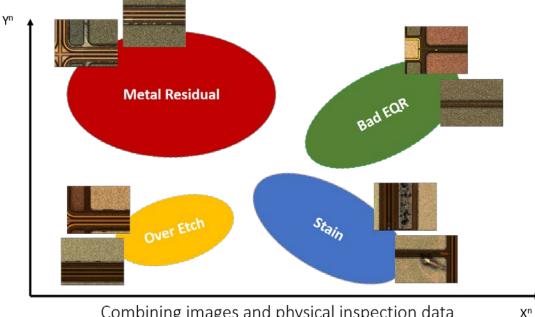


 Solution to autonomously classify defect patterns on Wafer Defect Maps (WDMs) in real time.

 Artificial Intelligence (AI) technique:

- Deep Learning (DL) algorithm
- specific Convolutional Neural Network (CNN) tailored to handle WDMs
- Solutions integrated in a quality inspection system

Use case: Automatic Defect Classification (ADC)



Combining images and physical inspection data

- Solution to autonomously classify all defects lying on the wafer in real time
- Artificial Intelligence (AI) technique: a **Random Forest algorithm**
- Label to each defect, specifying whether it has impact on device performances or not

- Advantages of the distributed approach (e.g. bandwidth, power consumption, privacy)
- Several application areas (e.g. winery, predictive maintenance) in IoT
- Support to manage complexity in semiconductor manufacturing (e.g. Automatic Wafer Classification, Automatic Defect Classification)

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Event organisers





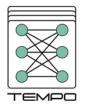




competitive leadership in the era of the digital economy. KDT JU is the successor to the ECSEL JU programme. <u>www.kdt-ju.europa.eu</u> The AI4DI project has received funding from the ECSEL Joint Undertaking (JU)

The Key Digital Technologies Joint Undertaking - the Public-Private Partnership for research, development and innovation – funds projects for assuring worldclass expertise in these key enabling technologies, essential for Europe's

The AI4DI project has received funding from the ECSEL Joint Undertaking (JU) under grant agreement No 826060. The JU receives support from the European Union's Horizon 2020 research and innovation programme and the national authorities. <u>www.ai4di.eu</u>



The TEMPO project has received funding from the ECSEL Joint Undertaking (JU) under grant agreement No 826655. The JU receives support from the European Union's Horizon 2020 research and innovation programme and Belgium, France, Germany, The Netherlands, Switzerland. <u>www.tempo-ecsel.eu</u>



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Thank You For your attention

